

TECHNICAL SPEC FOR Ion Implanter

System Model:

Axcelis GSD VHE

- Wafer size? 6 inch
- Wheel type? Full disk 17 wafers
- Wafer tilt? yes
- Source (i.e. Bernas or IHC)? bernas
- Extraction system (i.e. dual bellows)? Triple axes
- Gases? Boron, phosfine
- SDS Gas box? yes
- Max implantation energy (in KeV)? 5000
- Max Extraction voltage (in KeV)? 90
- Heat Exchanger? yes

- **Orienter type (flat, notched, etc...)? flat**
- **Hydrogen implantation available? no**
- **Number of trays?**
- **Load and unload locks:yes**
- **Source extraction alignment jig yes**
- **AMU yes**
- **Beamline column yes**
- **Mechanical clamp: yes**
- **Turbo type?**
- **PC type:**
- **Cryo type?**
- **PFS standard or HD? hd**